

## INTERNATIONAL SEARCH REPORT

International application No

PCT/FR2008/001427

A. CLASSIFICATION OF SUBJECT MATTER  
INV. H01L21/762

According to International Patent Classification (IPC) or to both national classification and IPC

## B. FIELDS SEARCHED

Minimum documentation searched (classification system followed by classification symbols)

H01L

Documentation searched other than minimum documentation to the extent that such documents are included in the fields searched

Electronic data base consulted during the international search (name of data base and, where practical, search terms used)

EPO-Internal, WPI Data, INSPEC

## C. DOCUMENTS CONSIDERED TO BE RELEVANT

Category*	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.
Y	US 2004/235266 A1 (TONG QIN-YI [US]) 25 November 2004 (2004-11-25) page 2, paragraph 42	1-20
Y	WU J-Y ET AL: "EFFECT OF THE WORKING GAS OF THE ION-ASSISTED SOURCE ON THE OPTICAL AND MECHANICAL PROPERTIES OF SiO <sub>2</sub> FILMS DEPOSITED BY DUAL ION BEAM SPUTTERING WITH SI AND SiO <sub>2</sub> AS THE STARTING MATERIALS" APPLIED OPTICS, OSA, OPTICAL SOCIETY OF AMERICA, WASHINGTON, DC, vol. 45, no. 15, 20 May 2006 (2006-05-20), pages 3510-3515, XP001242714 ISSN: 0003-6935 abstract page 3510, left-hand column, paragraph 1 page 3514, right-hand column, lines 4-13 ----- -/--	1-20

☒ Further documents are listed in the continuation of Box C.☒ See patent family annex.

## \* Special categories of cited documents:

- \*A\* document defining the general state of the art which is not considered to be of particular relevance
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Date of the actual completion of the international search

23 juin 2009

Date of mailing of the international search report

01/07/2009

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## C(Continuation). DOCUMENTS CONSIDERED TO BE RELEVANT

Category*	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.
A	US 2007/017438 A1 (XIE YA-HONG [US] ET AL) 25 January 2007 (2007-01-25) page 2, paragraph 29 page 3, paragraph 38 - page 4, paragraph 42 figures 2A-2E -----	1-20
A	RAY S. K. ET AL.: "Effect of reactive-ion bombardment on the properties of silicon nitride and oxynitride films deposited by ion-beam sputtering" JOURNAL OF APPLIED PHYSICS, vol. 75, no. 12, 15 June 1994 (1994-06-15), pages 8145-8152, XP002484791 abstract figure 1 -----	1-20
A	US 6 548 375 B1 (DE LOS SANTOS HECTOR J [US] ET AL) 15 April 2003 (2003-04-15) column 3, lines 53-59 -----	1-20
A	US 5 753 038 A (VICHIR MIROSLAV [US] ET AL) 19 May 1998 (1998-05-19) column 10, lines 18-29 -----	1-20
A	MOTOHIRO T ET AL: "GEOMETRICAL FACTORS OF ARGON INCORPORATION IN SiO <sub>2</sub> FILMS DEPOSITED BY ION BEAM SPUTTERING" THIN SOLID FILMS, ELSEVIER-SEQUOIA S.A. LAUSANNE, CH, vol. 120, no. 4, 1 October 1984 (1984-10-01), pages 313-327, XP000837083 ISSN: 0040-6090 abstract -----	1-20

# INTERNATIONAL SEARCH REPORT

Information on patent family members

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PCT/FR2008/001427

Patent document cited in search report	Publication date	Patent family member(s)	Publication date
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